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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q65755

Toshiyuki OGATA, et al.

Appln. No.: 09/922,723

Group Art Unit: 1752

Confirmation No.: 1261

Examiner: Sin J. Lee

Filed: August 07, 2001

For: POSITIVE RESIST COMPOSITION AND BASE MATERIAL CARRYING LAYER OF
THE POSITIVE RESIST COMPOSITION

STATEMENT OF SUBSTANCE OF INTERVIEW

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please review and enter the following remarks summarizing the interview conducted on
April 15, 2004:

REMARKS

An Examiner's Interview Summary Record (PTO-413) was attached with the Notice of
Allowance dated April 21, 2004.

The interview was initiated by the Examiner. Therefore, no further recordation by the
Applicant is believed to be required.

During the interview, the following was discussed:

1. Identification of claims discussed: 11-17.
2. Results of Interview: Agreement with respect to the claims was reached.

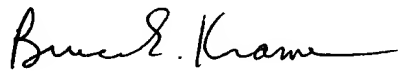
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Attorney Docket No.: Q65755

Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: In claims 11-17, the preamble will be changed from "A positive resist composition" to --A base material-- (these changes are being made to provide the correct preamble for claims 11-17).

It is believed that no petition or fee is required. However, if the USPTO deems otherwise, Applicant hereby petitions for any extension of time which may be required to maintain the pendency of this case, and any required fee, except for the Issue Fee, for such extension is to be charged to Deposit Account No. 19-4880.

Respectfully submitted,



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WASHINGTON OFFICE

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CUSTOMER NUMBER

Date: May 20, 2004